CEO, Dr. Nam Hun Kim

APTC, Republic of Korea

Dr. Nam-Hun Kim received a B.S. degree in Metallurgical Engineering from Seoul National University in 1980, and an M.S. degree in Materials Science & Engineering from KAIST(Korea Advanced Institute of Science and Technology) in 1982, and a Ph.D. degree in Materials Science and Engineering from Stanford University in 1992. His Ph.D. thesis was “Growth and Heat Treatment of Ternary Single Crystals(AgGaSe2) for Nonlinear Optical Applications”. Previously he worked on the development of electrical contact materials for OCB and GCB for high power applications at KERI in Korrea as a research engineer between 1982 and 1986. Also he worked on the development of the polymer-ceramic composite probe for acoustic transducers at Diasonics Ultrasound in Milpitas as a senior process engineer between 1992 and 1994. He worked on plasma etching(oxide etch and poly etch) at Applied Materials in Santa Clara as a senior engineering manager between 1994 and 2002. He received Dan Maydan Award in 1998. Then he returned to Korea and founded APTC in South Korea in 2002. Starting from 200mm oxide etcher, he developed various 200mm and 300mm plasma etchers such as oxide etcher, metal etcher, poly Si etcher, TSV, 150mm LED etcher, and 150mm/300mm plasma doping systems. He received manay awards including Korea Patent Award from Korea Prime Minister, The Korea’s 10 Best Technologies of 2005, and two Korea Presidential Awards(1985 & 2006). He also received Young Sil Jang’s Award(Invention Award) in 2007. He is the inventor of ACP (Adaptively Coupled Plasma) source. He actively takes part in product development, process development, productivity improvement and system troubleshooting including chamber matching. He currently holds 35 U.S. patents & more than 50 domestic patents.